



North America TC Chapter Metrics Global Technical Committee

Liaison Report
December 2025

STANDARDS

CONNECT - COLLABORATE. - INNOVATE. - GROW. - PROSPER

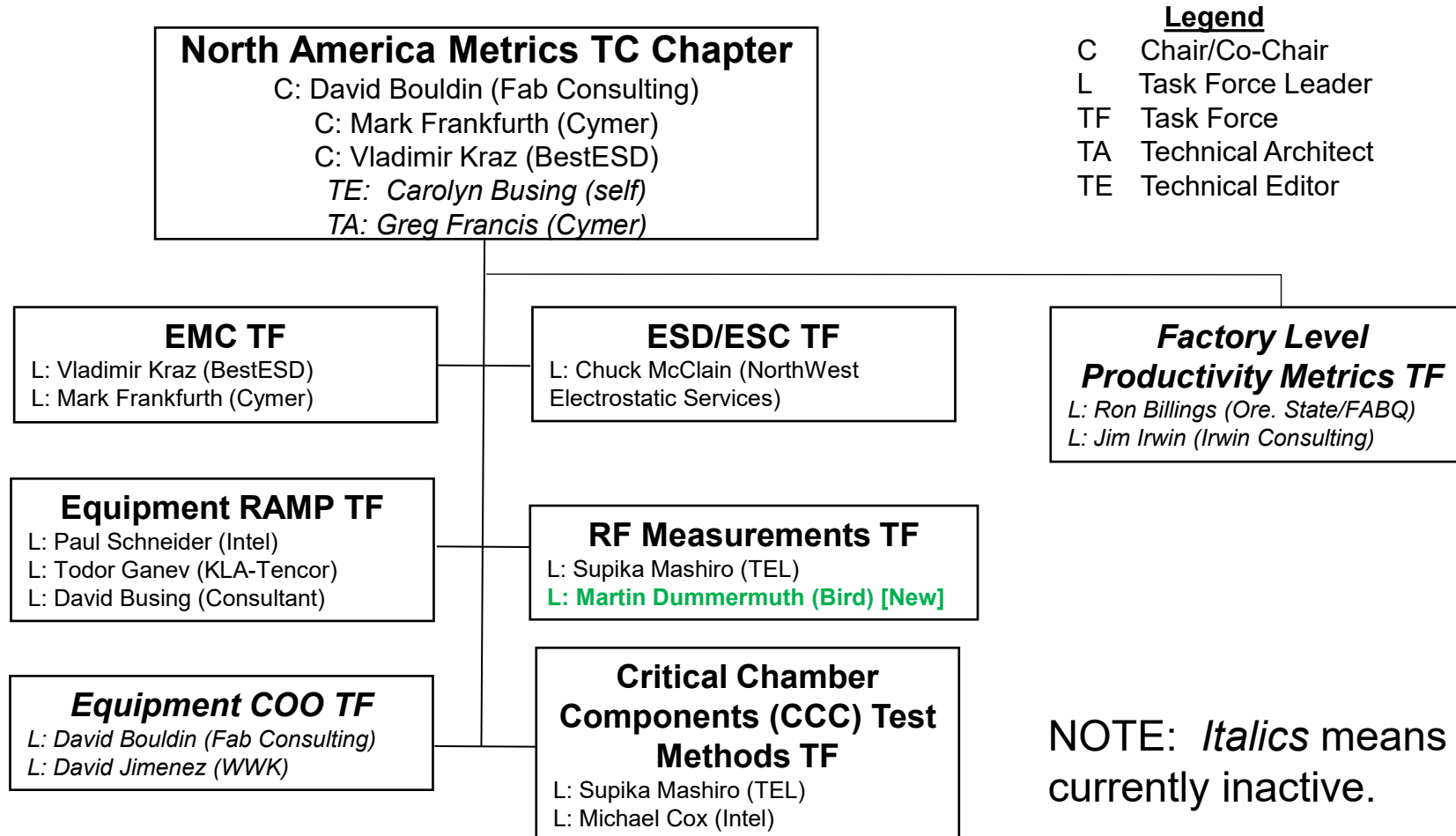
AGENDA

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Leadership

- N.A. Metrics TC Chapter Cochairs
 - David Bouldin (Fab Consulting)
 - Mark Frankfurth (Cymer)
 - Vladimir Kraz (BestESD)
- TC Leadership Changes
 - None
- TF Leadership Changes
 - Martin Dummermuth (Bird Technologies) approved as RF Measurements TF Co-Leader

Organization Chart



NOTE: *Italics* means group is currently inactive.

Meeting Information

- Last Meeting
 - Thursday, October 9, 2025
 - SEMICON West
- Next Meeting
 - Thursday, February 12, 2026
 - Online via Web Conference

Ballot Results

- None

Activities Authorized by GCS between TC meetings

#	Type	SC/TF/WG	Details
None			

Authorized Activities

Activities authorized during TC Chapter Meeting

- Reapproval of SEMI E180-1220 - Test Method for Measuring Surface Metal Contamination Through ICP-MS of Critical Chamber Components Used in Semiconductor Wafer Processing

Authorized Ballots

Ballots authorized during TC Chapter Meeting

#	When	TF	Details
TBD	Cycle 9-2025	CCC TF	Reapproval of SEMI E180-1220 - Test Method for Measuring Surface Metal Contamination Through ICP-MS of Critical Chamber Components Used in Semiconductor Wafer Processing

Standard(s) to receive Inactive Status

Activities authorized during TC Chapter Meeting

- None

5-Year Review

Display Name	Description	Task Force	Disposition
SEMI E180-1220	Test Method for Measuring Surface Metal Contamination Through ICP-MS of Critical Chamber Components Used in Semiconductor Wafer Processing	Metrics TC	Reapprove

Task Force Updates

EMC Task Force

- Leadership Changes
 - None
- Ballots
 - None
- Other Activities
 - Intel has proposed changes to SEMI E33/176
 - Zachary Joseph/Intel was asked to present his suggestions on gradation of ELF/VLF levels including discussions with Intel suppliers of relevant equipment
 - Since Intel did not join the meeting, the leader suggested putting this activity on hold.

Equipment RAMP Metrics Task Force

- Leadership Changes
 - None
- Ballots
 - None
- Other Activities
 - The task force is continuing work on revising the E10 and E79 webinar

Critical Chamber Components (CCC) Test Methods Task Force

- Leadership Changes
 - None
- Ballots
 - 7324 – New Standard: Guide to Using a Liquid Particle Counter to Assess Particulate Surface Contamination on Critical Chamber Components and Coupons **[Published as SEMI E194]**
 - R7130C – New Standard: Test Method Using Adhesive Replacement Substrates to Assess Particulate Surface Contamination of Critical Chamber Components **[Published as SEMI E195]**
- Other Activities
 - SNARF 7167, New Standard: Test Method for Measuring and Characterizing Surface Particle Contamination on Critical Chamber Components with Airborne Particle Counter and Dry Aerosolizing Chamber, is being reviewed



THANK YOU

STANDARDS